

Resource Summary Report

Generated by RRID on Aug 6, 2026

FEI: V400ACE Focused Ion Beam for Semiconductors

RRID:SCR_019912

Type: Tool

Proper Citation

FEI: V400ACE Focused Ion Beam for Semiconductors (RRID:SCR_019912)

Resource Information

URL: <https://www.fei.com/products/fib/v400ace-focused-ion-beam-for-semiconductors/>

Proper Citation: FEI: V400ACE Focused Ion Beam for Semiconductors (RRID:SCR_019912)

Description: Focused ion beam system that can be configured for backside editing with an optional IR microscope and bulk silicon trenching package.

Resource Type: instrument resource

Keywords: FEI, FIB Microscope, Instrument Equipment, USEDiT,

Availability: Commercially available

Resource Name: FEI: V400ACE Focused Ion Beam for Semiconductors

Resource ID: SCR_019912

Alternate IDs: Model_Number_V400ACE

Record Creation Time: 20220129T080347+0000

Record Last Update: 20260801T190635+0000

Ratings and Alerts

No rating or validation information has been found for FEI: V400ACE Focused Ion Beam for Semiconductors.

No alerts have been found for FEI: V400ACE Focused Ion Beam for Semiconductors.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.